

Application Data Sheet

Application Information

Application number::

Filing Date::

Application Type::

Regular

Subject Matter::

Utility

Title ::

BEAM IRRADIATION
APPARATUS, BEAM
IRRADIATION METHOD,
AND METHOD FOR
MANUFACTURING THIN
FILM TRANSISTOR

Attorney Docket Number::

0756-7295

Total Drawing Sheets::

5

Small Entity?::

No

Applicant Information

Applicant Authority Type::

Inventor

Primary Citizenship Country::

Japan

Given Name::

Koichiro

Middle Name::

Family Name::

TANAKA

Name Suffix::

City of Residence::

Atsugi

State or Province of Residence::

Kanagawa

Country of Residence::

Japan

Street of mailing address:: c/o Semiconductor Energy
Laboratory Co., Ltd.
398, Hase
City of mailing address:: Atsugi-shi
State or Province of mailing address:: Kanagawa-ken
Country of mailing address:: Japan
Postal or Zip Code of mailing address:: 243-0036

Correspondence Information

Correspondence Customer Number :: 31780
E-Mail address:: erobinson@riplo.com

Representative Information

Representative Customer Number:: 31780

Domestic Priority Information

Application ::	Continuity Type::	Parent Application::	Parent Filing Date::

Foreign Priority Information

Country::	Application number::	Filing Date::	Priority Claimed::
Japan	2003-116392	04/21/2003	Yes

Assignee Information

Assignee name::	Semiconductor Energy Laboratory Co., Ltd.
Street of mailing address::	398 Hase
City of mailing address::	Atsugi-shi
State or Province of mailing address::	Kanagawa-ken
Country of mailing address::	Japan
Postal or Zip Code of mailing address::	243-0036